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On the cutting edge of semiconductor sensors: towards intelligent X-ray detectors

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Noise power spectra: row dependence

This appendix shows the power spectra of the individual noise components as a function of row number for the detectors studied in Chapter 6. The detectors are operated at a bias voltage that corresponds to a lateral diffusion with a standard deviation of 10 μm and the threshold is set at ~ 20 keV.

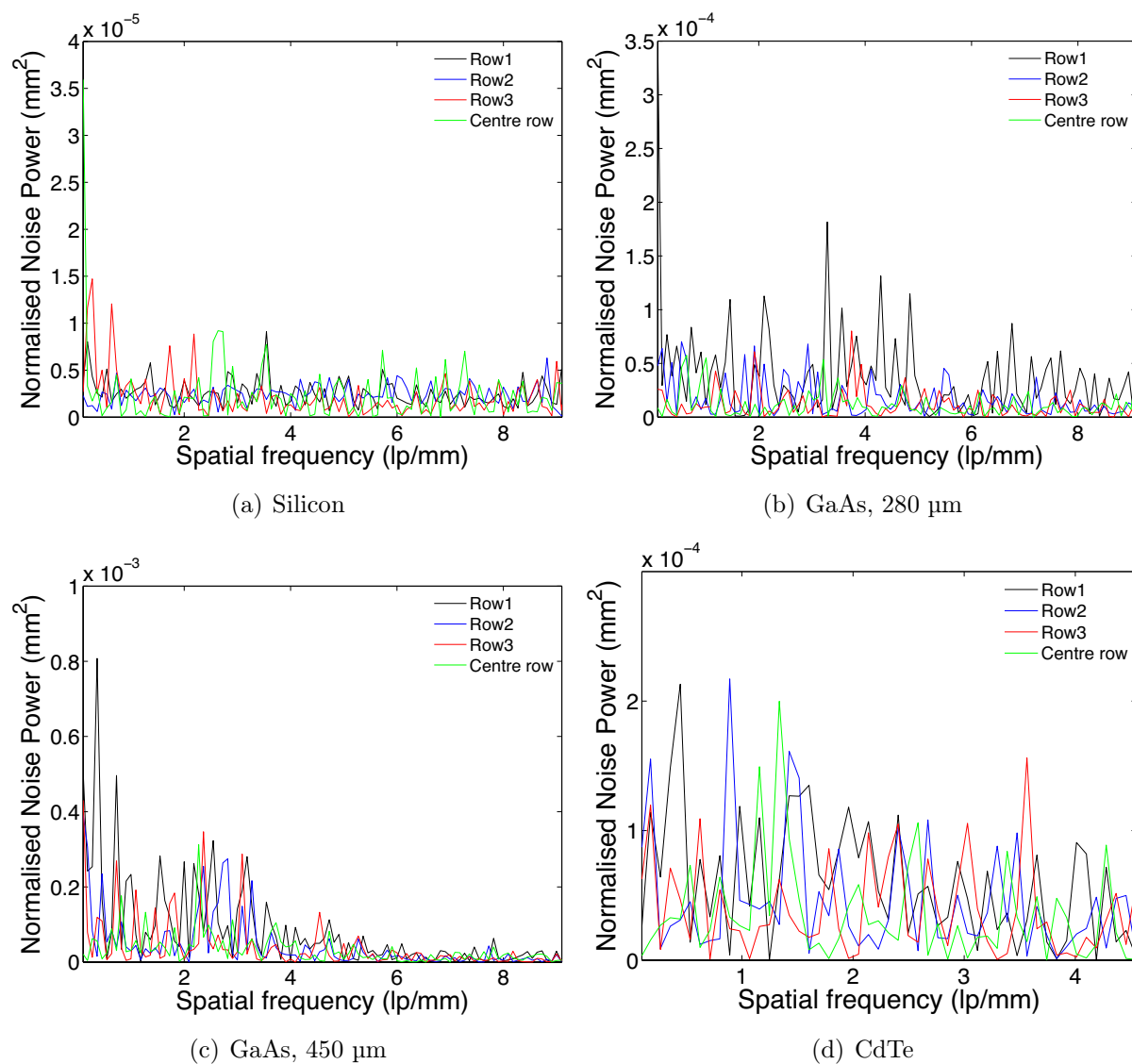


Figure E.1: Row dependence – fixed-pattern noise

Power spectra of the fixed-pattern noise of the three outermost rows compared to that of the centre row.

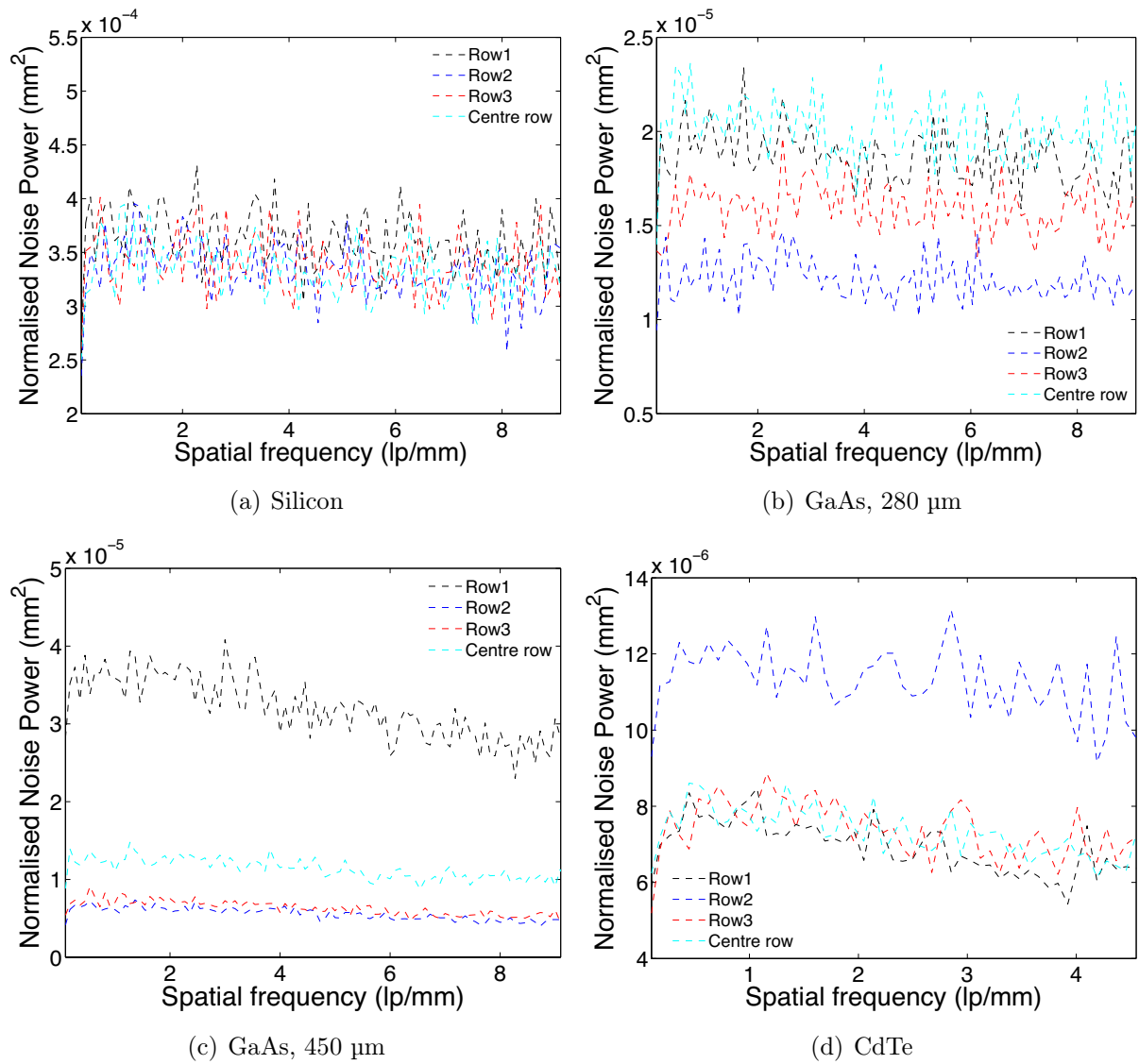


Figure E.2: Row dependence – stochastic noise

Power spectra of the stochastic noise of the three outermost rows compared to that of the centre row.